

“The 37th European Mask and Lithography Conference”

EMLC 2022

will take place

Monday, June 20th – Wednesday, June 22nd, 2022

at the

KU in Leuven, Belgium



Jubilee Hall for Exhibition & Posters



Conference Room

EMLC 2022 – Already Confirmed Presentations:

Tutorial



Peter De Bisschop
IMEC



Rogier Verberk
TNO



Takeo Watanabe
University of Hyogo

Keynote



Luc Van den Hove
IMEC



Frank E. Abboud
INTEL



Jos Benschop
ASML

Invited



Lena Bachar
Carl Zeiss SMS



Ingo Bork
Siemens EDA



Jo Finders
ASML



Dirk Hellweg
Carl Zeiss SMT



Vicky Philipson
IMEC



Heike Riel
IBM Research



Thomas Schmidt
AMTC



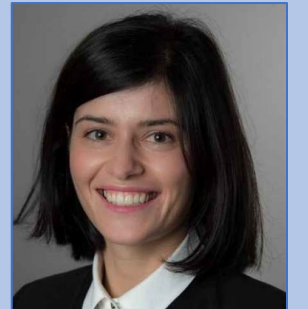
Frank Sundermann
ST Microelectronics



Anna Tchikoulaeva
Lasertec



Raluca Tiron
CEA LETI



Taguhi Yeghoyan
YOLE

to be defined

**Best Paper of
BACUS 2021**

to be defined

**Best Paper of
PMJ 2022**

Tuesday, June 21st, 2022

Conference Dinner at the Faculty Club



Thursday, June 23rd, after EMLC 2022: Visit at



Organized by Kurt Ronse

Director Advanced Patterning Program at imec

and

Uwe Behringer UBC Microelectronics, EMLC2022 Conference Chair

ABSTRACT DUE DAY: April 15th, 2022

www.emlc-conference.com